

PARAMETRIC STUDIES FOR FOLDED-BEAM SUSPENSION OF MEMS GYROSCOPE

**V. USHA SHREE, P. RAMANA RAO, P. CHANDRA SEKHAR REDDY,
M. SREENIVASULU, P. SRIKANTH AND M. ARUN KUMAR**

Abstract

In this paper variations in Micro-Electro-Mechanical-System (MEMS) sensors gyroscope suspension design have been explored. Designs that utilize in-plane and out-of-plane sensing and resonant frequency are studied Design and analysis of poly-silicon gyroscopes have been carried out.

Keywords: In-plane and out-of-plane stiffness, resonant frequency, MEMS gyroscope